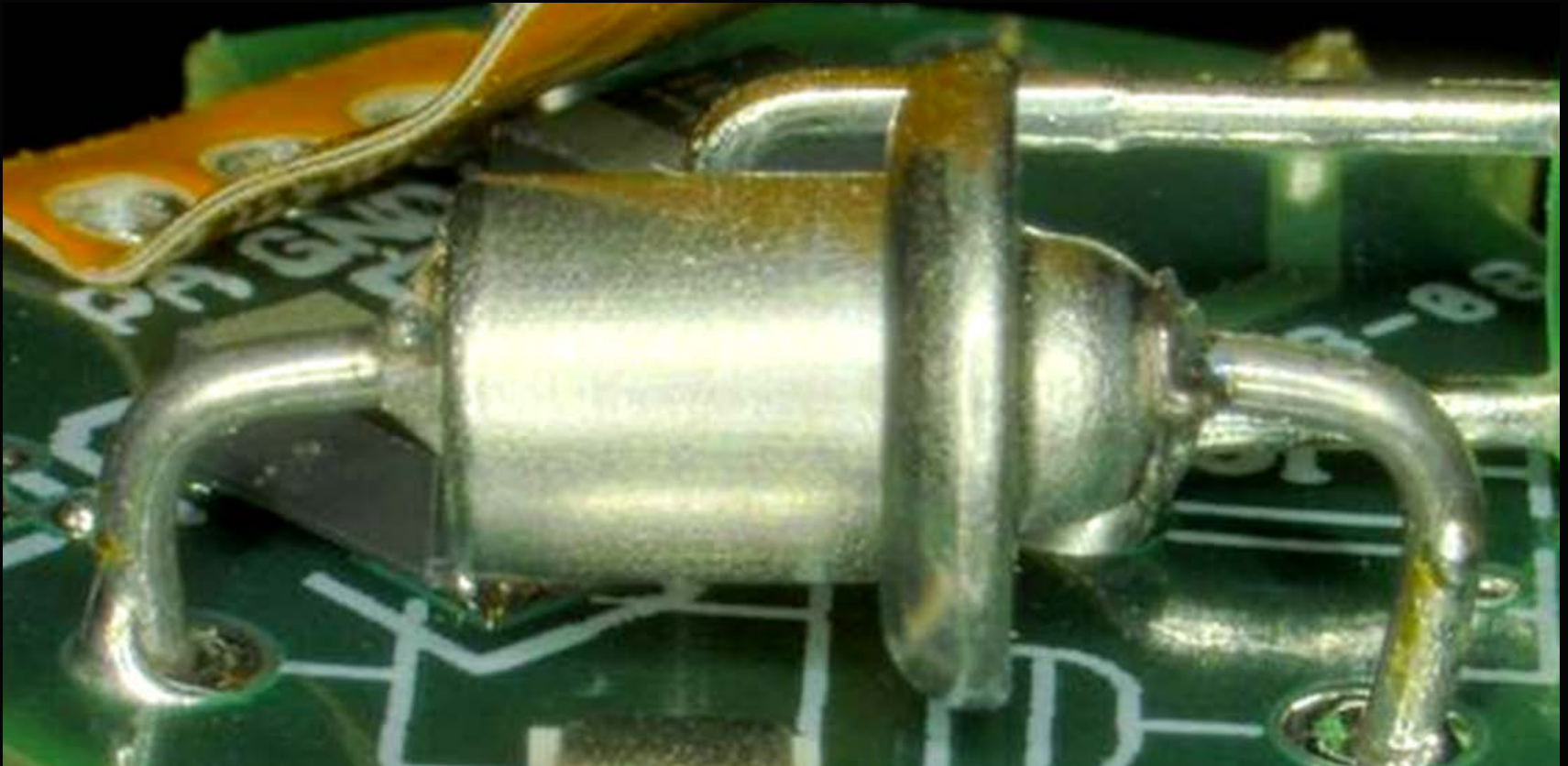
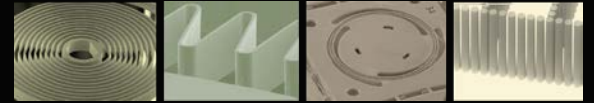
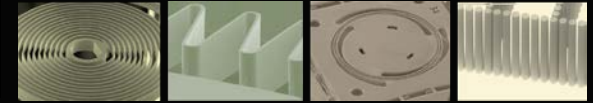


Low G MEMS Inertia Switches for Fuzing Applications

*HT MicroAnalytical, Inc.
Sam Rogers, Danny Czaja, Hopper Chu,
Todd Christenson, Chairman & CTO*

todd.c@htmicro.com





Issues

Reliability

Scaling

Approach

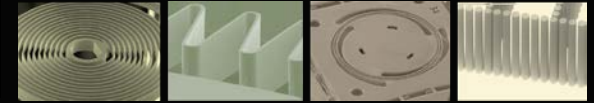
Design

Fabrication

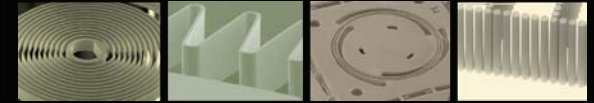
Results

Initial Testing

Reliability

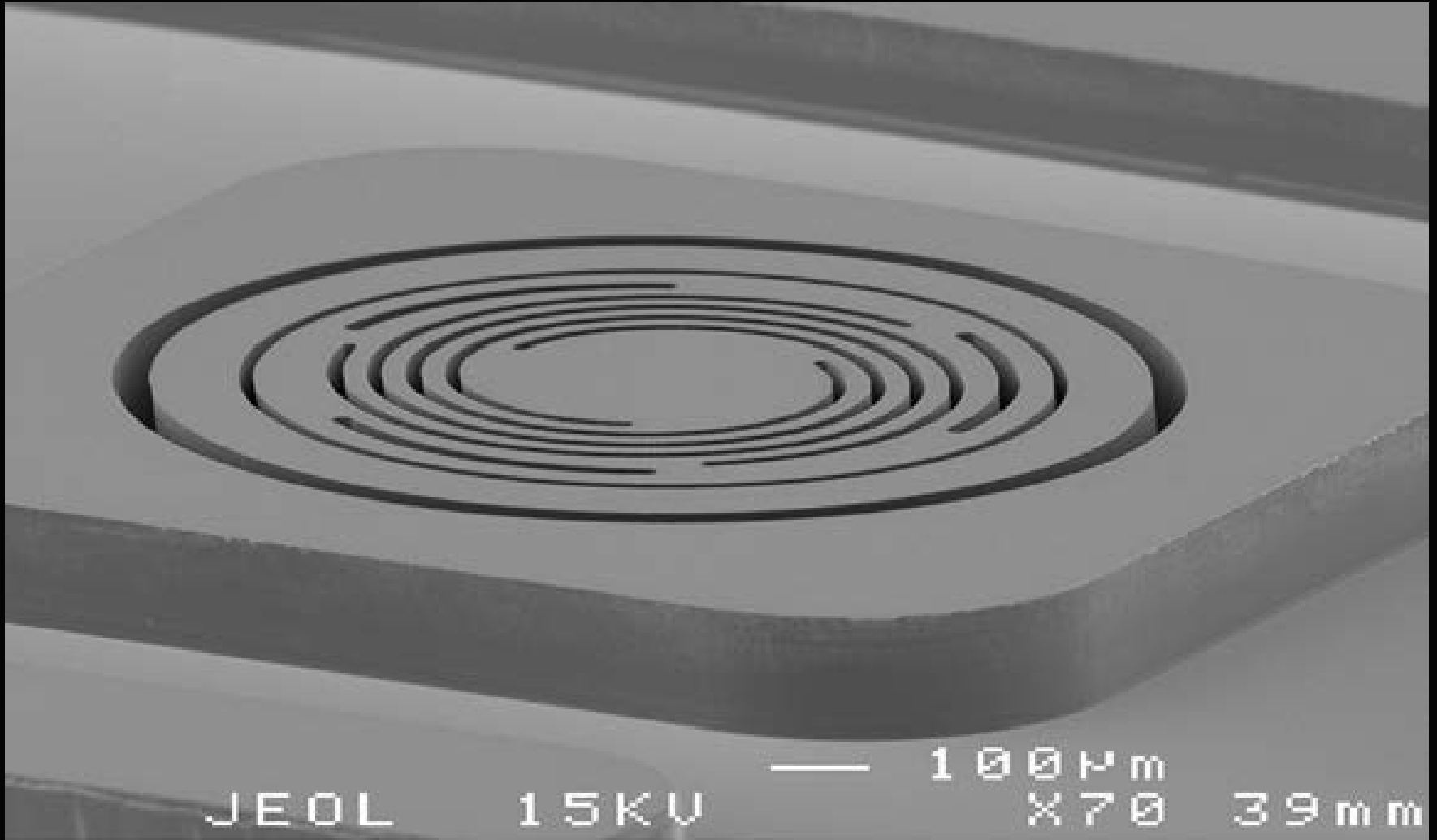
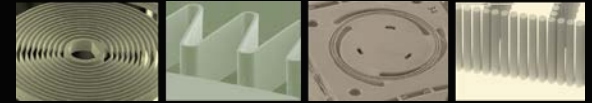


• Reliability \Rightarrow Force \Rightarrow Δ Energy \Rightarrow Volume

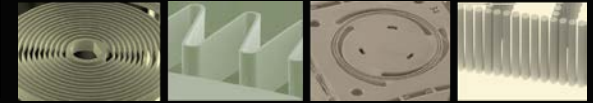


$$F_{ctct} = (ma - kx_{ctct})$$

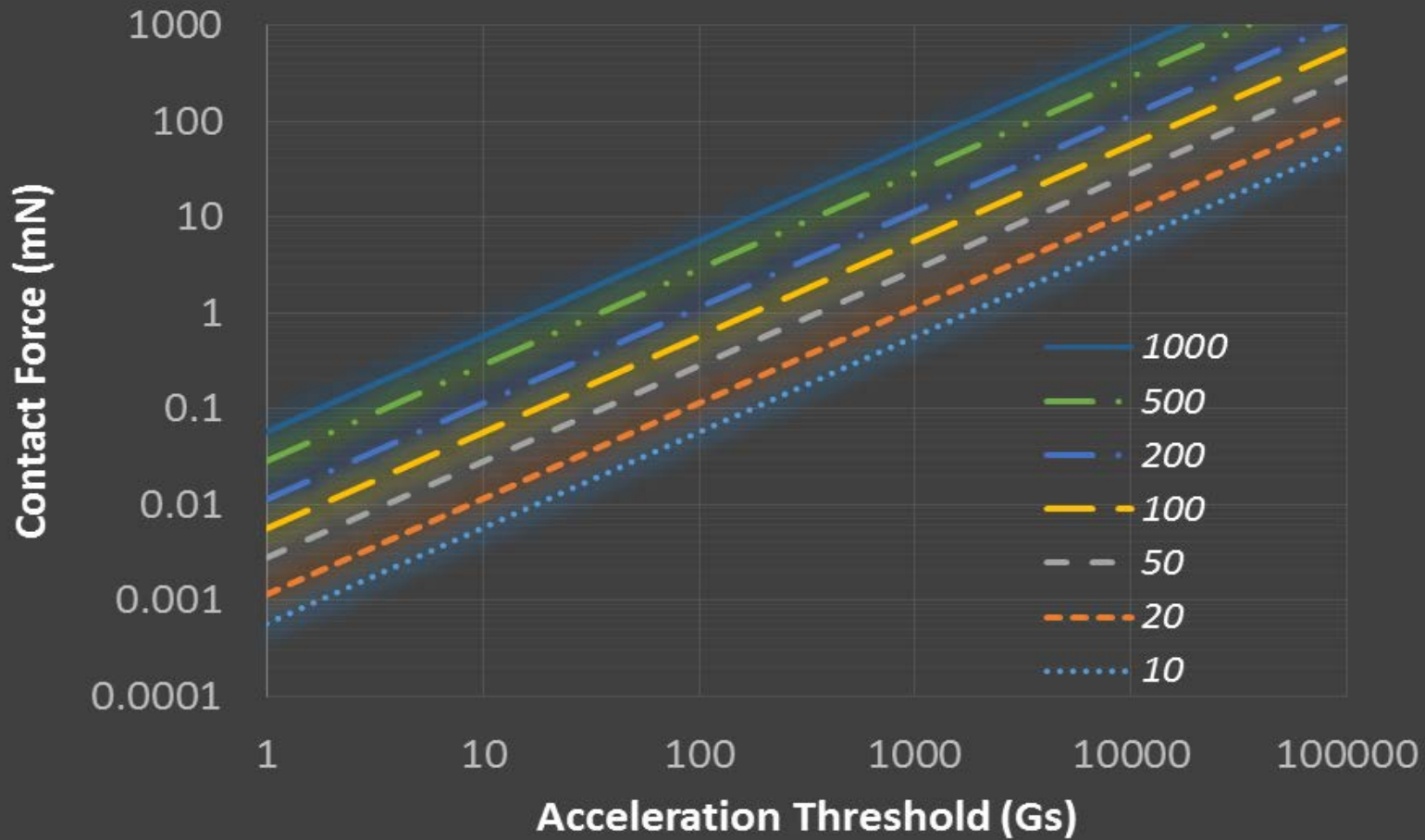
Design



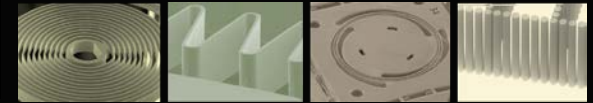
Reliability



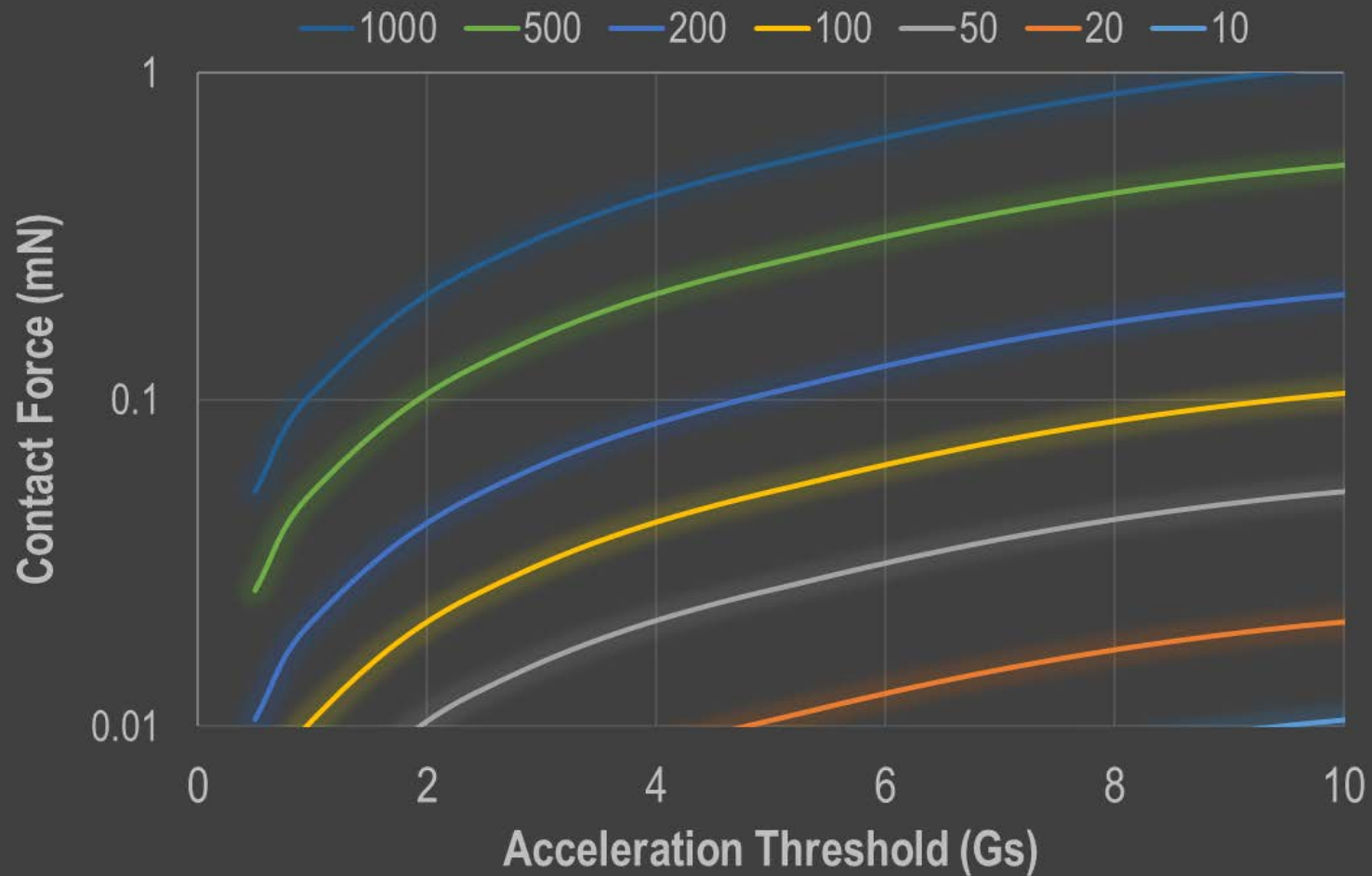
Force at 25% overdrive versus acceleration for varying proof mass thickness



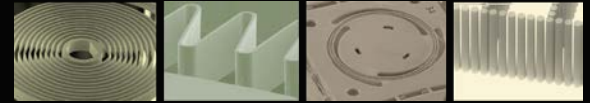
Design



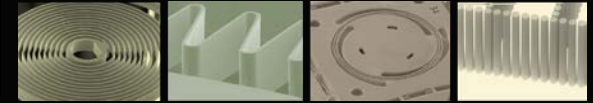
Force at 25% overdrive versus acceleration for varying proof mass thickness



Design



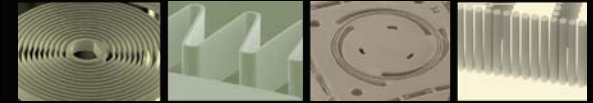
$$FOM \sim \frac{F\eta}{\$A} \sim \frac{\rho h\eta}{\$}$$



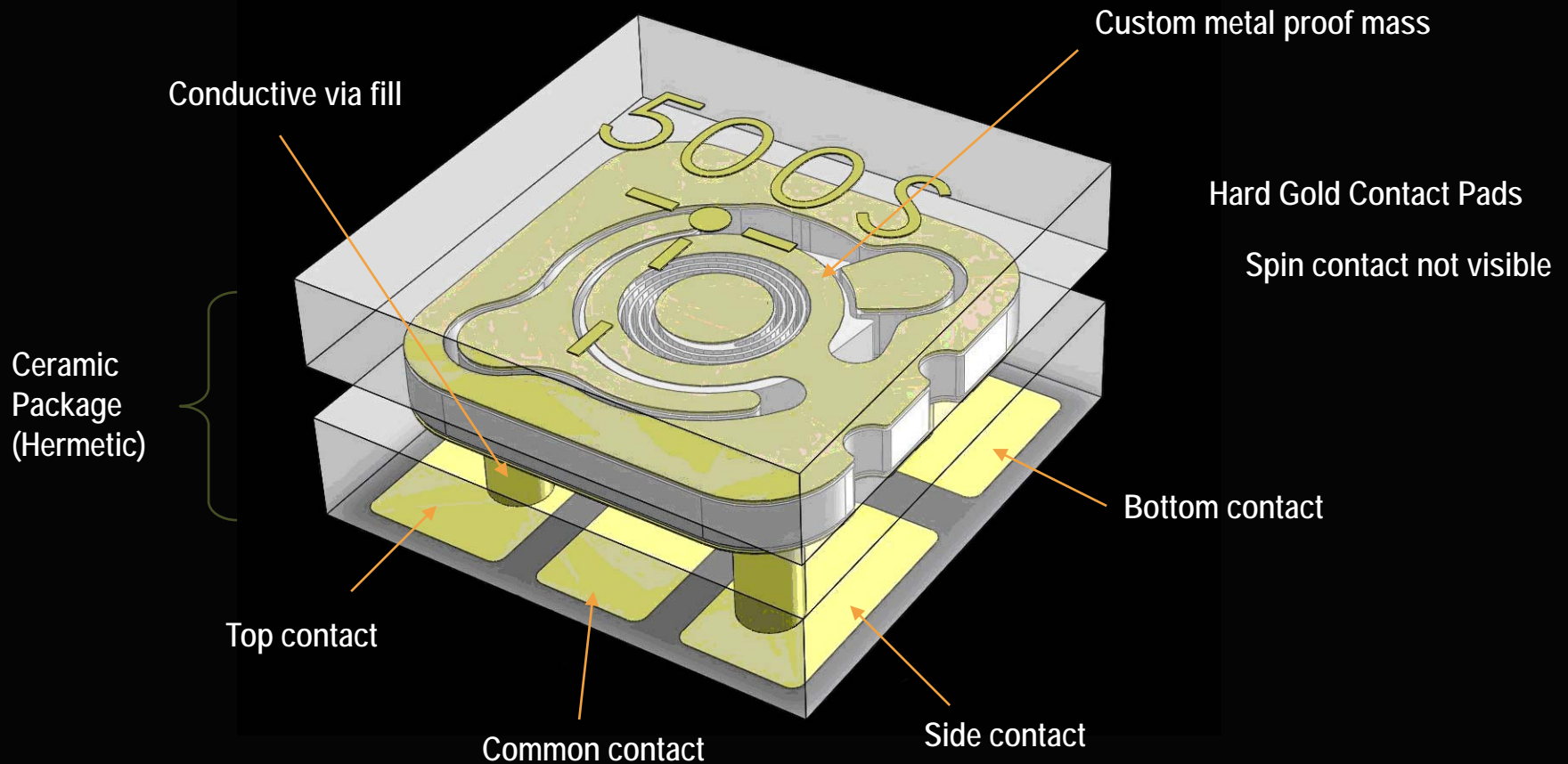
Keys for High FOM / Viable Microfabricated Component

- 1) Materials – ρ , σ_y , σ - n - \$
- 2) High Aspect Ratio - \$
- 3) Tolerances / Integration / Packaging - \$
- 4) Testing - \$

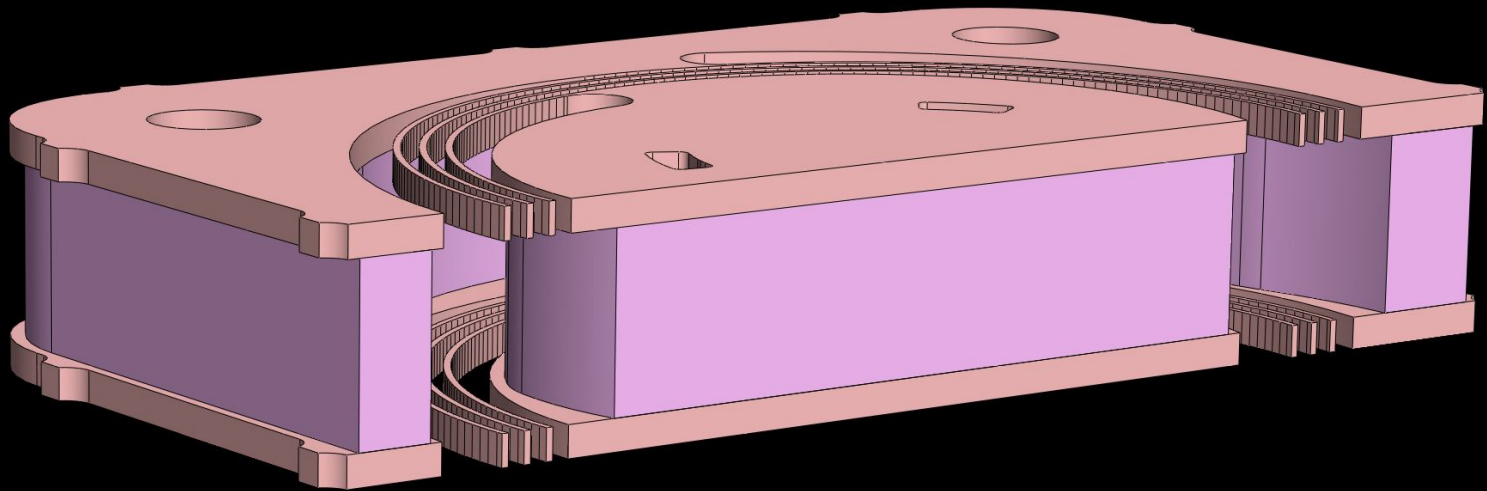
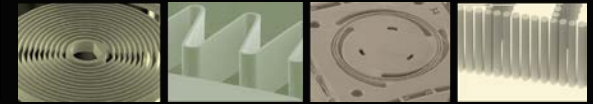
Design



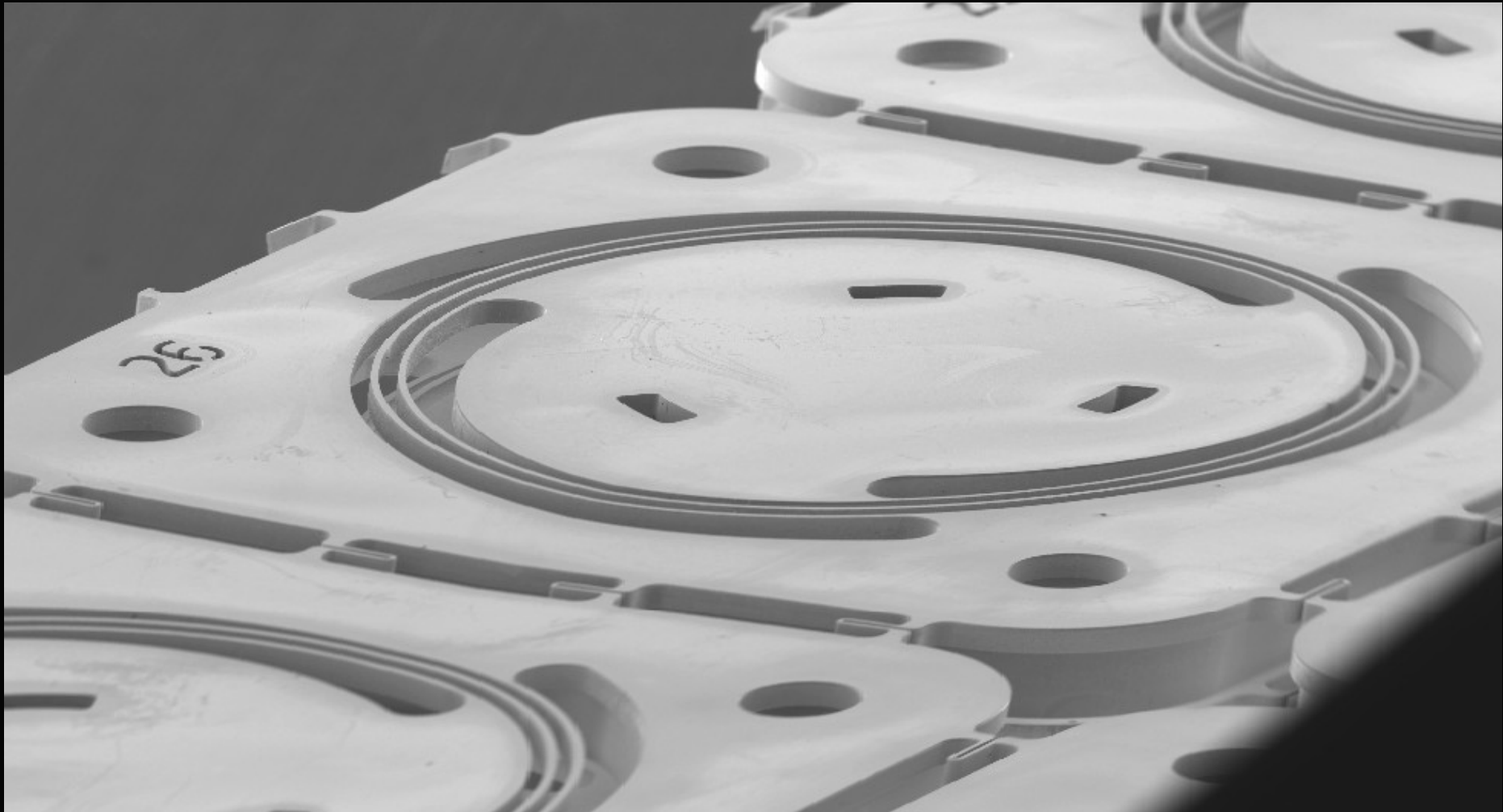
Integrated Inertia Switch Anatomy



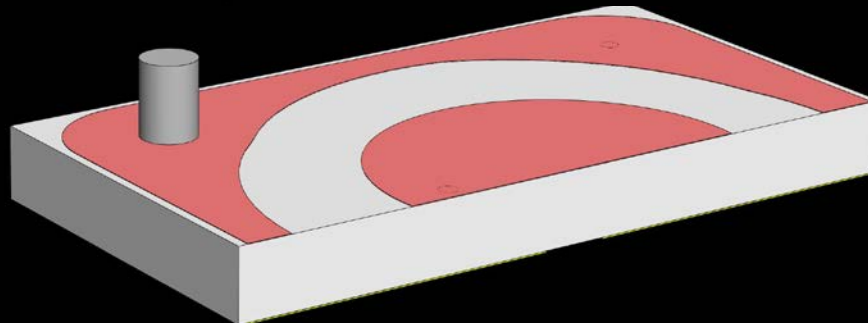
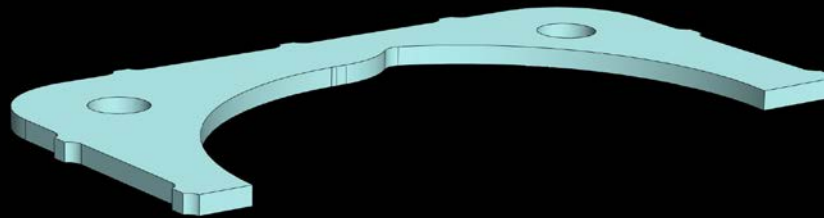
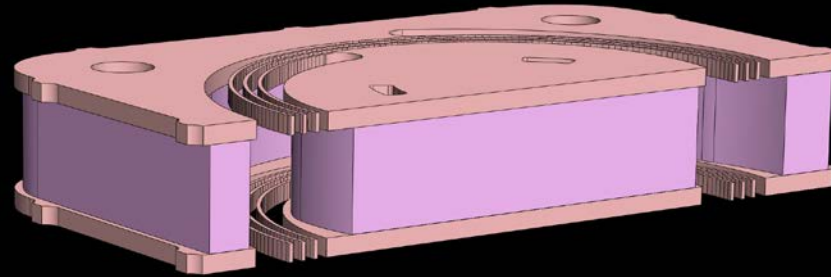
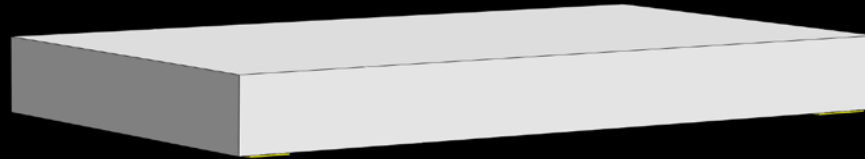
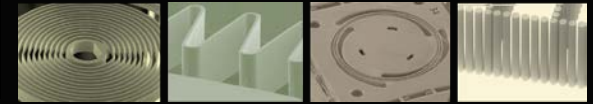
Multi-layer spring-mass fabrication



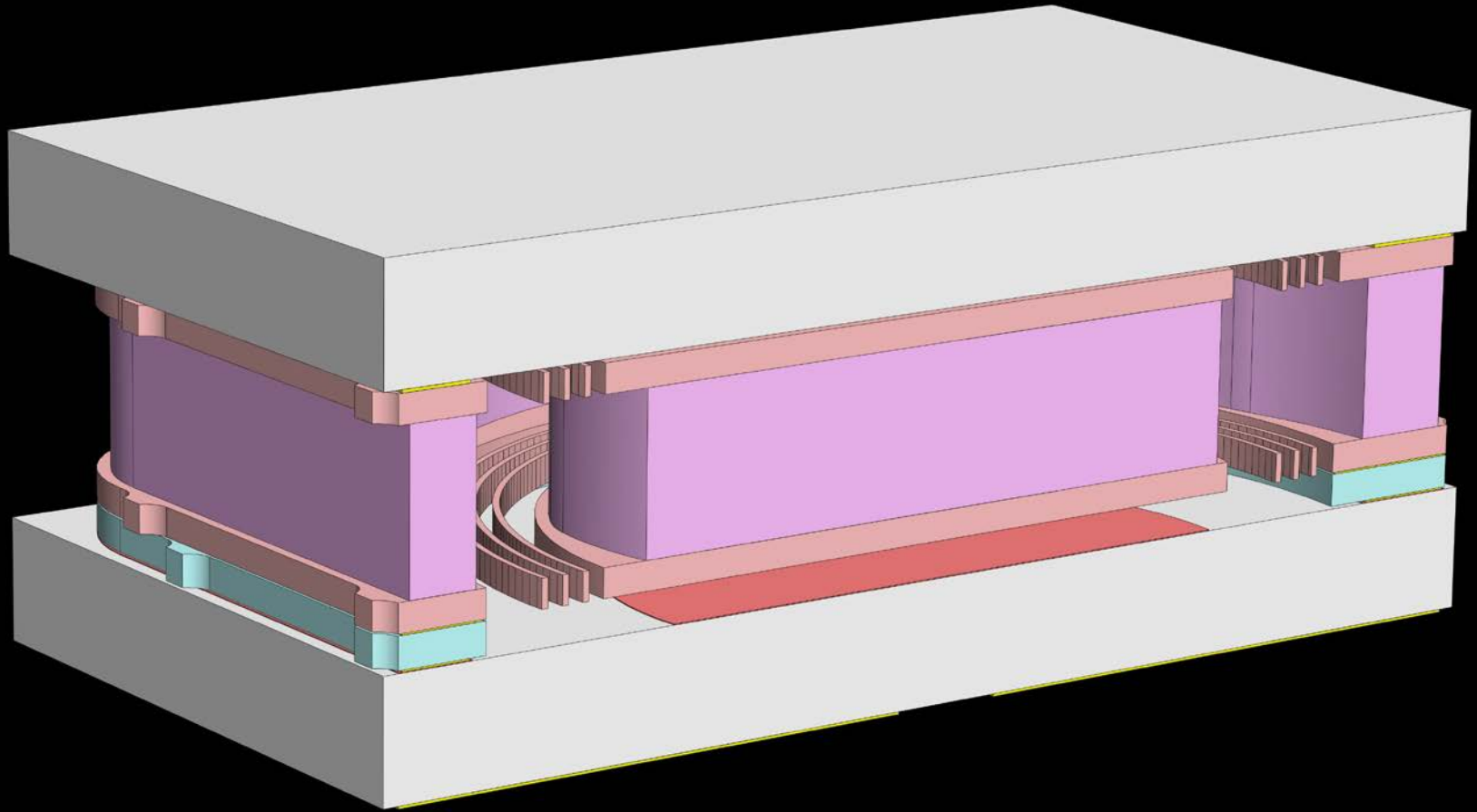
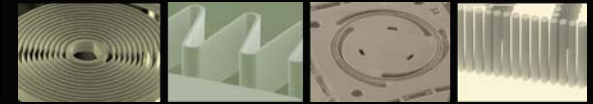
multi-layer fabrication



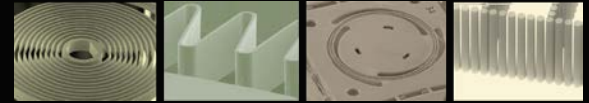
Multi-layer spring-mass fabrication



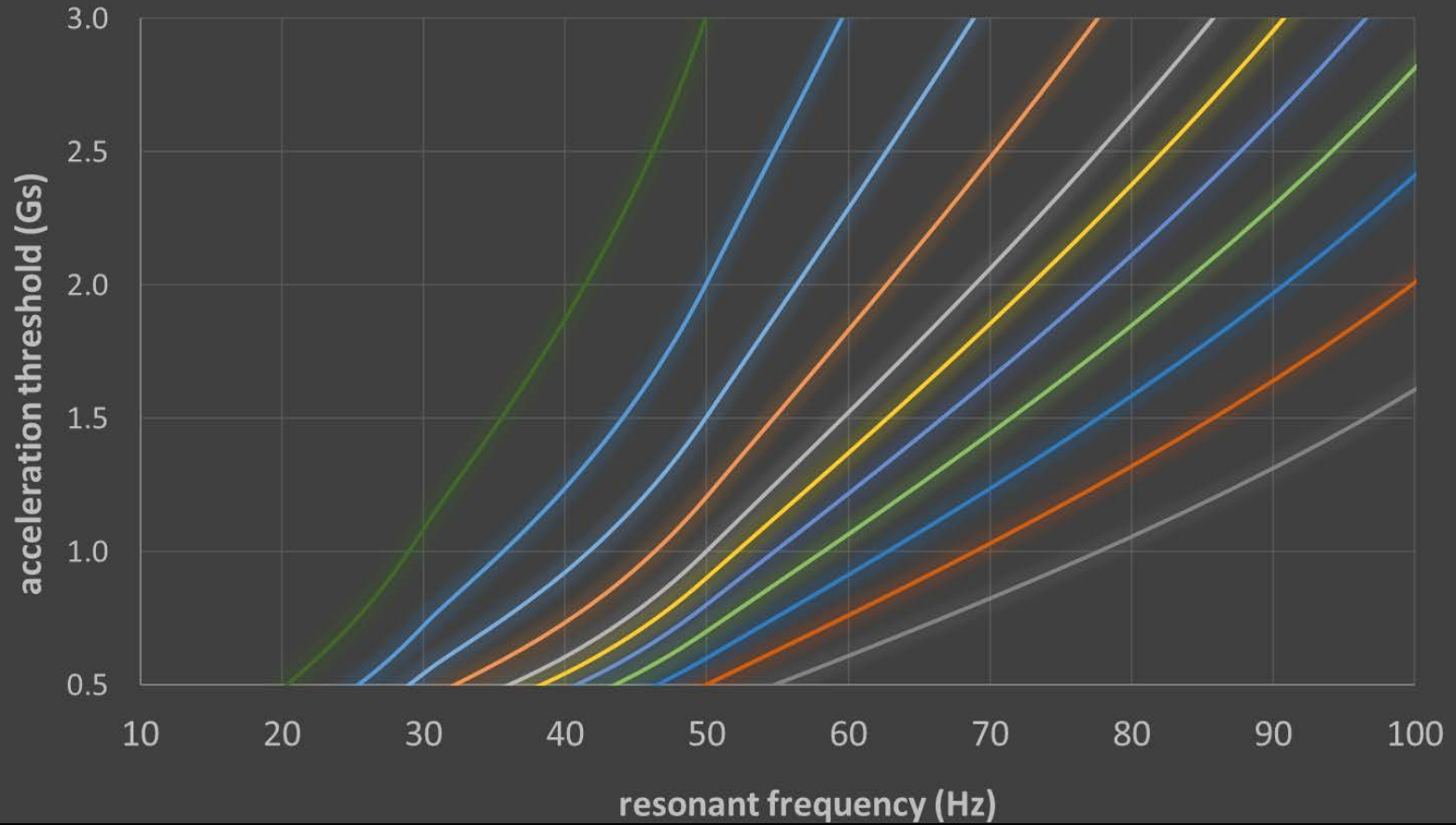
Multi-layer spring-mass fabrication



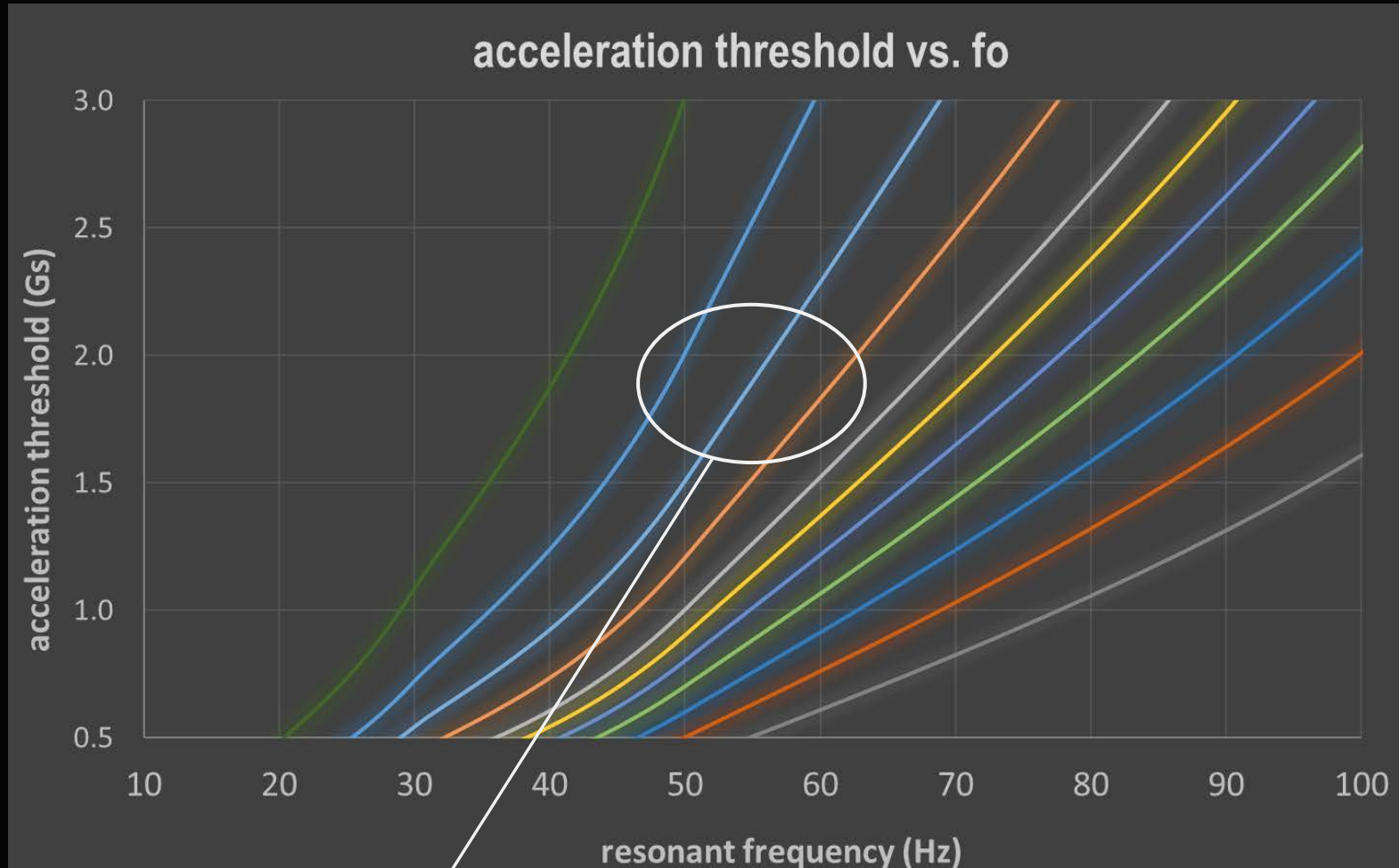
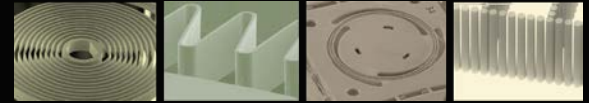
$$ma = kx$$



acceleration threshold vs. f_0

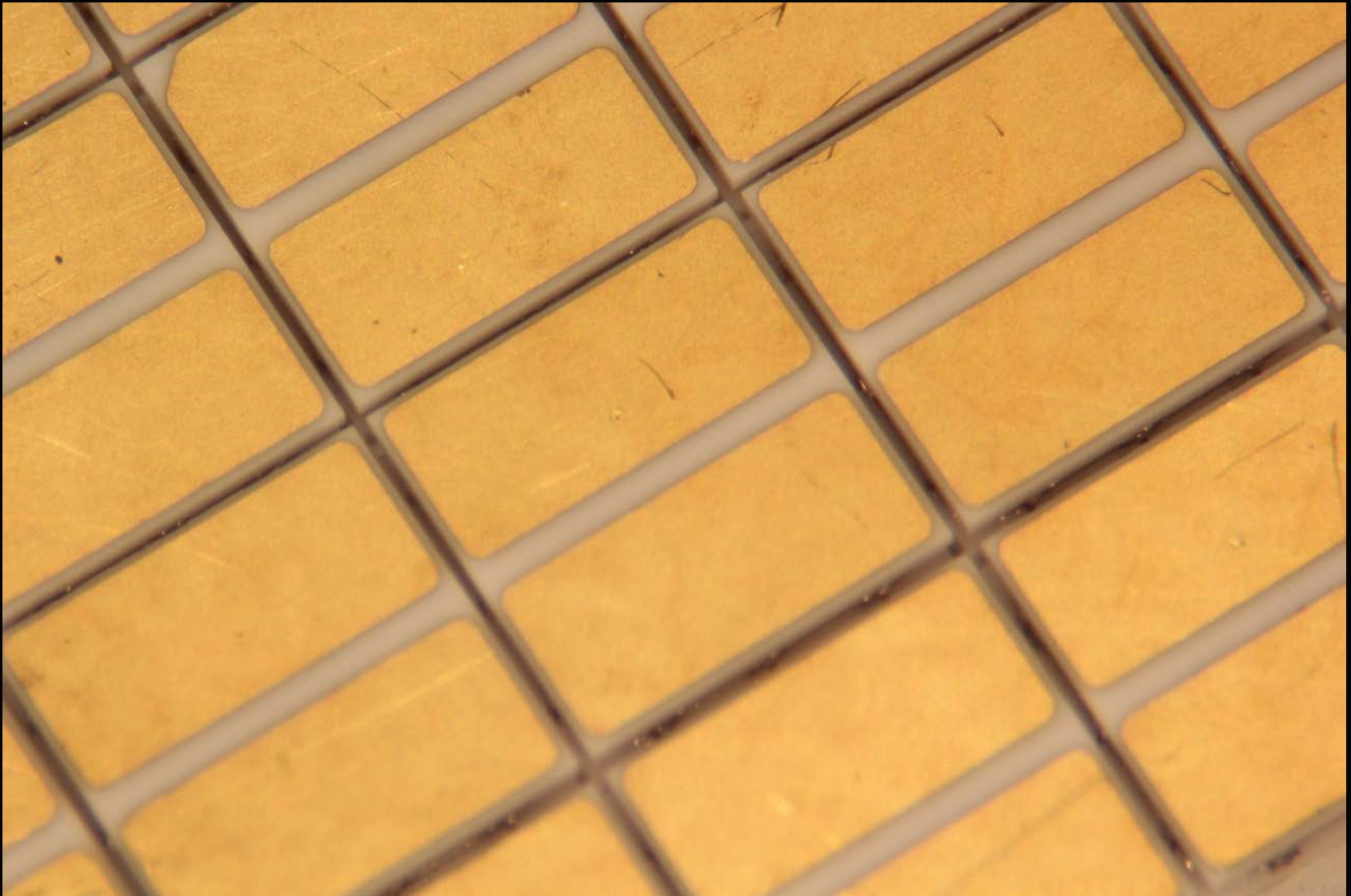
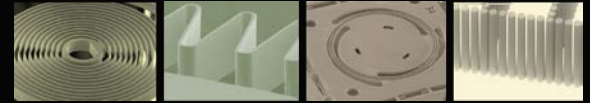


$$ma = kx$$

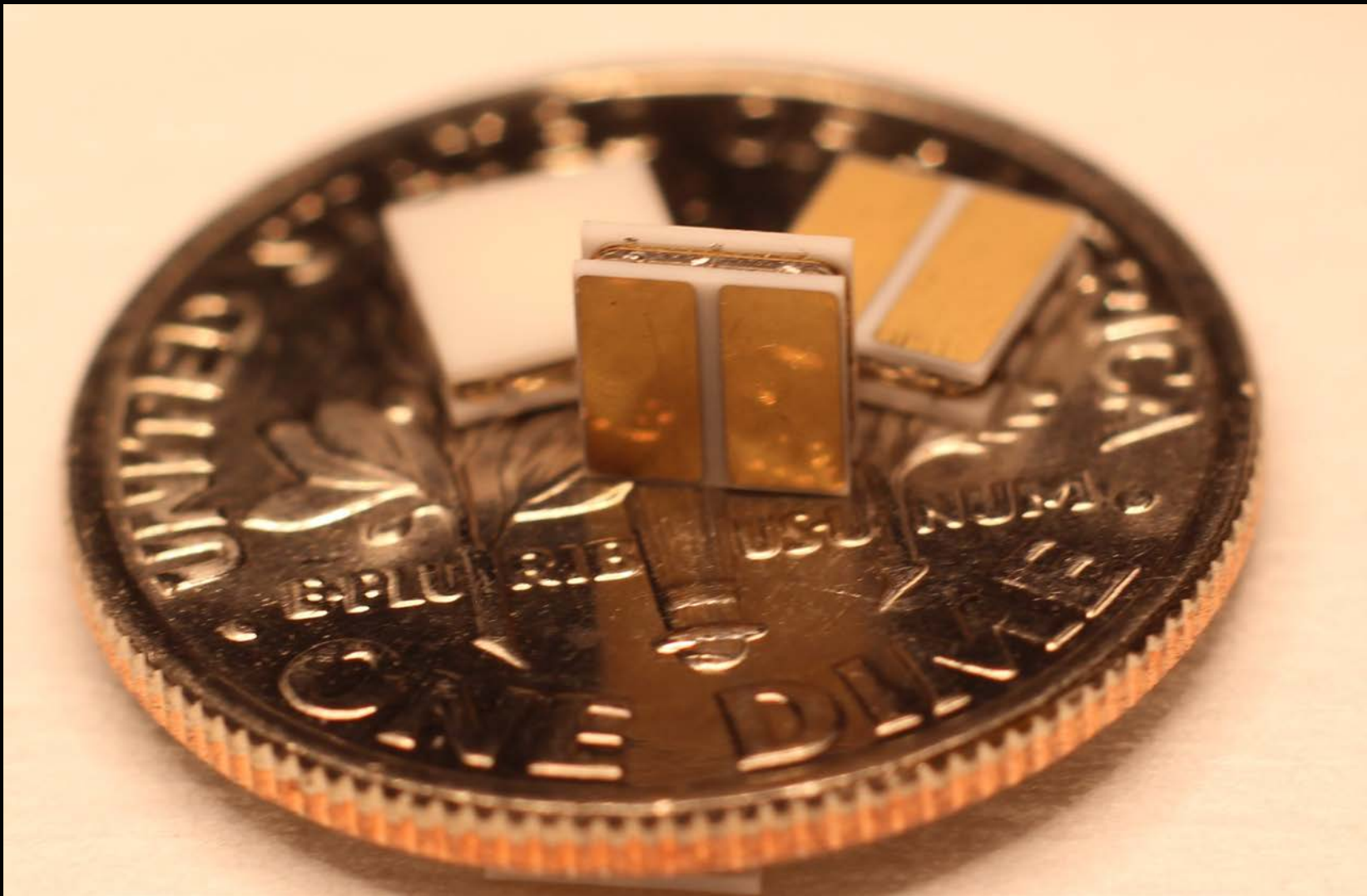
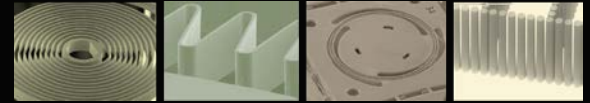


~ 0.05 G / Hz

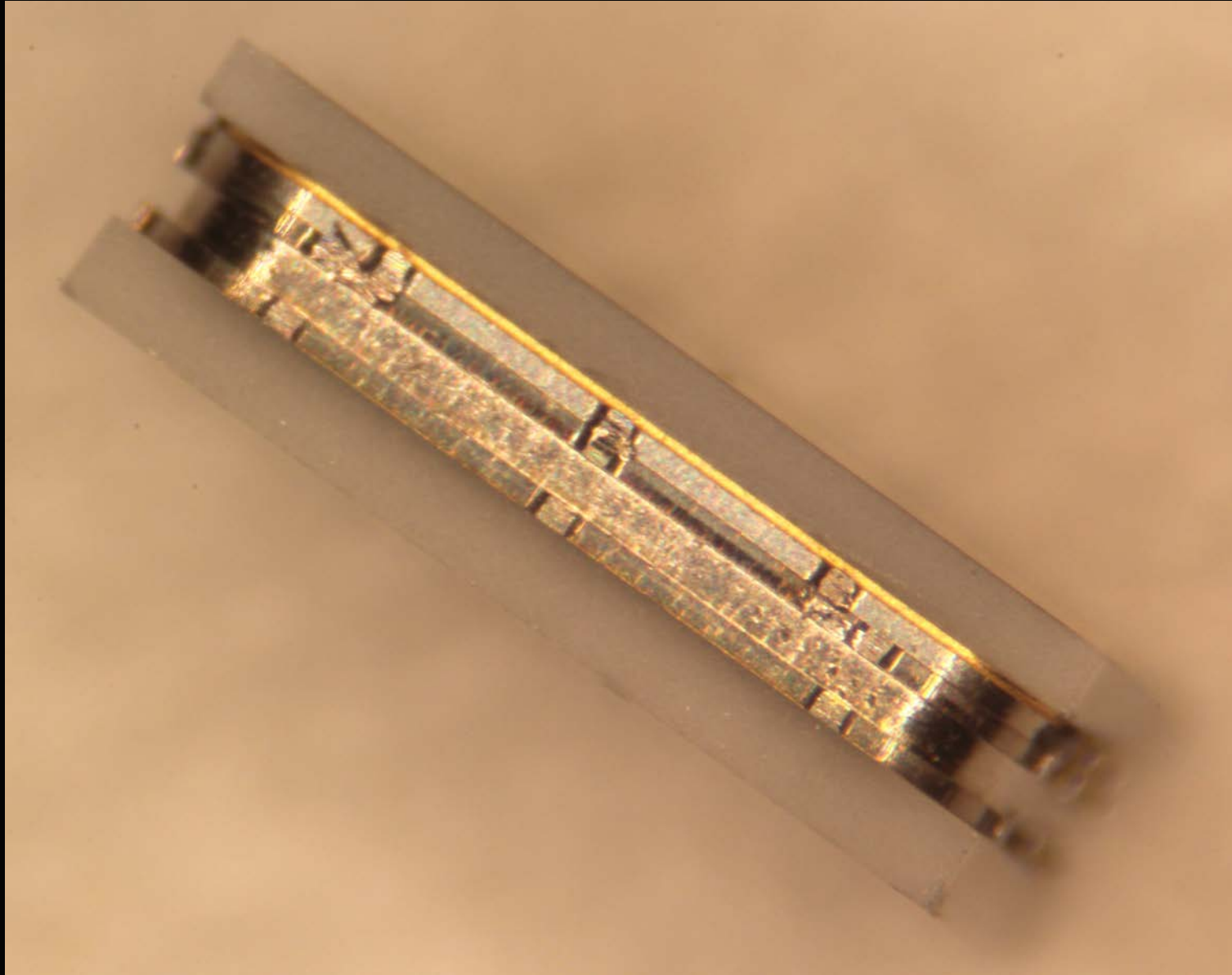
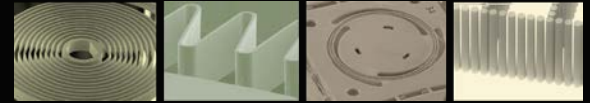
Diced Wafer



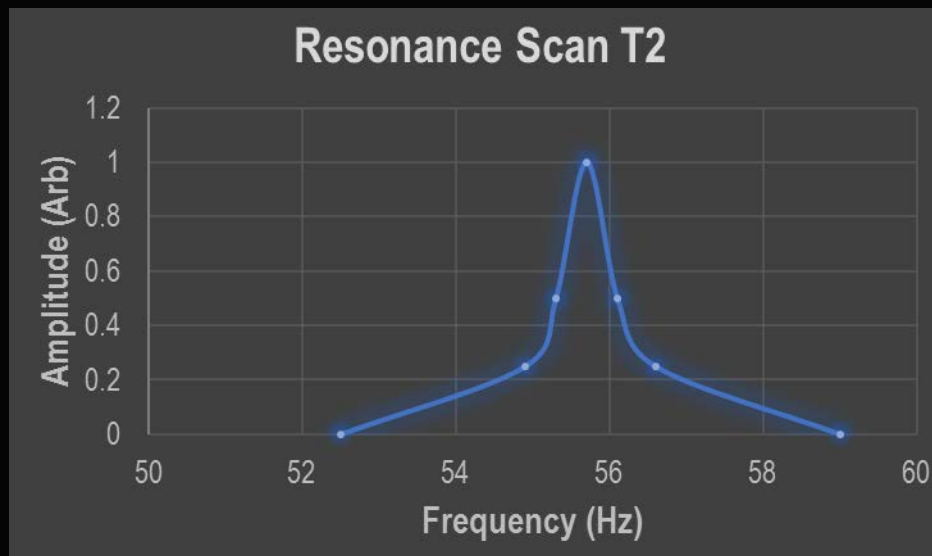
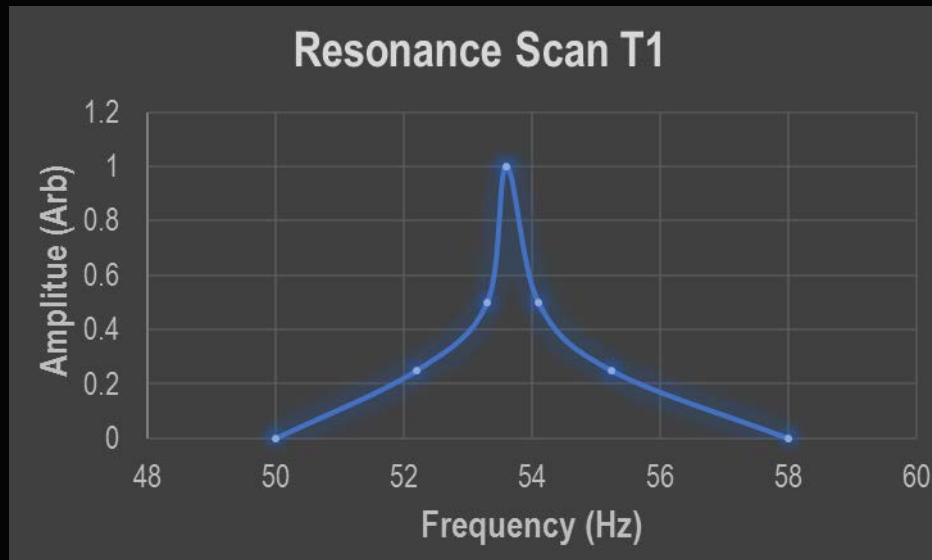
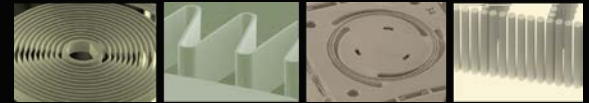
'WLP' Diced Parts



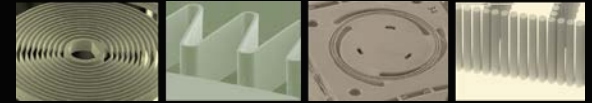
Edge of Device



Resonance Measurements



Acknowledgements



Ryan Knight (ARL)

Daniel Jean (Indian Head)

Edward Cornell (China Lake)

Thank You!



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